

Application No.	Applicant(s)	
10/720,444	TAKAHASHI ET AL.	
Examiner	Art Unit	
Paul D. Kim	3729	

SEARCHED					
Class	Subclass	Date	Examiner		
29	592.1 602.1 603.07 603.12 603.15	4/19/2005	PK		
	603.16 603				
360	235.7 235. %				
	236.3 236.5				
	236.6 237				
428	212 216				
	336 426				
	428 432				
	701 702				
438	455-459 69				
	745 753				
369	112.01 300	·			
	112.05 118				
451	5,41	<i>V</i>			

INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner	
SAME AS ABOVE		8/11/2005	PK	

SEARCH NOTES (INCLUDING SEARCH STRATEGY)			
	DATE	EXMR	
Reviewed Parent Application 09/585,428 (US PAT. 6,680,900)	4/19/2005	PK	
PLUS Search	4/19/2005	PK	
Text Search EAST/NPL (IEEE)	4/20/2005		
Updated Text Search EAST	8/11/2005	PK	
	- 1 -		